· · · · · · · · · · · · · · · · · · ·	Application No.	Applicant(s)
Notice of Allowability	10/679,454	KATO, YOSHIAKI
	Examiner	Art Unit
	Zia R. Hashmi	2881
The MAILING DATE of this communication appeal claims being allowable, PROSECUTION ON THE MERITS IS nerewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RID of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in the or other appropriate communic GHTS. This application is sub-	is application. If not included cation will be mailed in due course. THIS
1. This communication is responsive to 10/7/2003.		
2. ☑ The allowed claim(s) is/are <u>20-28</u> .		
3. $igotimes$ The drawings filed on <u>07 October 2003</u> are accepted by the	e Examiner.	
 4. Acknowledgment is made of a claim for foreign priority ur a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 	been received. been received in Application N	No
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		reply complying with the requirements
5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give		
6. CORRECTED DRAWINGS (as "replacement sheets") mus (a) including changes required by the Notice of Draftspers 1) hereto or 2) to Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date ldentifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in the search sheet in the search sheet in the search sheet is should be labeled as such in the search sheet in the search sheet in the search sheet is should be labeled as such in the search sheet in the search sheet in the search sheet is should be labeled as such in the search sheet in the search sheet in the search sheet is should be labeled as such in the search sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet in the search sheet is sheet in the search sheet in the search sheet is sheet in the search sheet sheet in the search sheet in the search sheet in the search sheet s	son's Patent Drawing Review (. s Amendment / Comment or in .84(c)) should be written on the c	the Office action of
 DEPOSIT OF and/or INFORMATION about the depo attached Examiner's comment regarding REQUIREMENT 	sit of BIOLOGICAL MATER	IAL must be submitted. Note the
Attachment(s) 1. ☐ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 10/7/03 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ☐ Interview Sum Paper No./Ma 08), 7. ☐ Examiner's An	ail Date

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DETAILED ACTION

Allowable Subject Matter

- 1. In accordance with the "Preliminary Amendment", claims 1-19 have been canceled.
- 2. Claims 20-28 are allowed.
- 3. The following is an examiner's statement of reasons for allowance:

With respect to independent claims 20, 21, and 23, prior art fails to disclose a mass spectrometer (MS) comprising a first ions source for ionizing sample, and a second ion source producing ions of a polarity reversed from that one of the ions produced by the first ion source; an ion deflector for introducing and deflecting ions from the first and second ion sources; an ion-trap mass spectrometer with a ring and end cap electrodes; a detector for detecting ions from first and second ion sources introduced through the ion deflector into the ion-trap MS; a third ion source for ionizing the sample to be measured; a fourth ion source producing ions of a polarity reversed from that of the third ion source; and a second ion deflector arranged between the ion-trap mass spectrometer and the detector.

In the prior art, one of the difficulties encountered in analyzing the mass spectrum of product ions complicated by multiply-charged ions resulting in high m/z ions is that they can be subjected to mass spectrometry like a single-charged ions. As an example, in mass spectrometry of proteins and DNAs, a protein having a mass of 30,000 gives multiply-charged ions of 30 valences, has an m/z of 1,000, which can be

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subjected as single-charged ions having the mass of 1,000. Most proteins and peptides give positive multiply-charged ions, and the DNAs give negative multiply-charged ions. However, these multiple charges can be reduced by ion/ion reactions, which makes it possible to discriminate the multiply-charged ions of a large mass from the chemical noises (caused by impurities) of a low mass region. Moreover, the MS to which the ion/ion reactions are applied in the prior art is only an ion-storage type mass spectrometer, i.e. the ion-trap mass spectrometer. The small-sized mass spectrometer such as the ion-trap mass spectrometer has a limited mass range to be measured, so that the biological high mass molecules such as protein or DNA, can be measured only because they are multiply-charged ions. If the ion/ion reactions are utilized to eliminate the superposition of the mass spectrum over the chemical noises, the biological high molecules go out of measuring range so that they cannot be measured.

The present invention has been conceived to solve such problems and has an object to provide a mass spectrometer system capable of easily improving the efficiency of a charge reduction due to ion/ion reactions and applying the ion/ion reactions even when used with a variety of mass spectrometers. The present invention provides a mass spectrometer system of the components described above, and is characterized in that the ions from the first and second ion sources are mixed between the first and second ion sources, and then introduced together into the mass spectrometer. There is further provided a mass spectrometer system for mass spectrometry of a sample to be measured by ionizing the sample, comprising: a first ion source for ionizing the sample; a second ion source for producing ions of a polarity reversed from that of the ions

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produced in the first ion source; a quadrupole mass spectrometer for the mass

spectrometry of the ions coming from the first ion source; an rf multipole ion guide

for producing product ions of the ions ejected from the quadrupole mass spectrometer;

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an ion deflector for introducing and deflecting the ions coming from the rf multipole ion

guide and the second ion source; a mass spectrometer for the mass spectrometry of the

ions ejected from the ion deflector; and a detector for detecting the ions ejected from the

mass spectrometer. The mass spectrometer system is characterized in that the ions

from the first ion source and the ions from the second ion source are caused to collide

in said rf multipole ion guide.

Claims 22 and 24-28 are allowed by virtue of their dependencies on the

independent claims 20, 21 and 23.

Conclusion

4. Any inquiry concerning this communication or earlier communications from the

examiner should be directed to Zia Hashmi whose telephone number is (571) 272-2473.

The examiner can normally be reached between 8.30 AM- 5 PM. If attempts to reach

the examiner by telephone are unsuccessful, the examiner's supervisor, John R. Lee

can be reached on (571) 272-2477.

Zia Hashmi

April 3, 2004.

JOHN R. LEE
ECHTSONY PATENT EXAMINER
ECHTSON OGY CENTER 2800